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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet 1 of 2

Complete if Known	
Application Number	10/679,100
Filing Date	October 3, 2003
First Named Inventor	Steve Berger
Art Unit	2881
Examiner Name	James L. Leybourne
Attorney Docket Number	MIM-067.02

U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No.[1]	Document Number: Number-Kind Code[2] (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
JLL	A	US- 4,609,809	02SEP86	Yamaguchi	
JLL	B	US- 4,634,871	06JAN87	Knauer	
JLL	C	US- 4,661,709	28APR87	Walker	
JLL	D	US- 4,694,178	15SEP87	Harte	
JLL	E	US- 4,820,898	11APR89	Slingerland	
JLL	F	US- 4,874,460	17OCT89	Nakagawa	
JLL	G	US- 4,876,112	24OCT89	Kalto et al.	
JLL	H	US- 4,894,549	16JAN90	Stengl	
JLL	I	US- 5,051,556	24SEP91	Sakamoto	
JLL	J	US- 5,093,572	03MAR91	Hosono	
JLL	K	US- 5,149,974	22SEP92	Kirch et al.	
JLL	L	US- 5,188,705	23FEB93	Swanson	
JLL	M	US- 5,270,552	12DEC93	Ohnishi et al.	
JLL	N	US- 5,376,791	27DEC94	Swanson et al.	
JLL	O	US- 5,435,860	25JUL95	Rasmussen	
JLL	P	US- 5,674,280	12NOV96	Fujii et al.	
JLL	Q	US- 5,827,786	27OCT98	Puretz	
JLL	R	US- 5,945,677	31AUG99	Leung	
JLL	S	US- 6,011,269	04JAN00	Veneklasen	

FOREIGN PATENT DOCUMENTS

Examiner Initials*	Cite No.[1]	Foreign Patent Document: Country Code[3]-Number[4]-Kind Code[5] (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages Or Relevant Figures Appear	T[6]
JLL	T	DE3910054A1	11OCT90	Germany		
JLL	U	EP0257685B1	09JAN91	EPO		
JLL	V	JA6169125	09APR86	Japan-Abstract		
JLL	W	WO0076954	14DEC00	WIPO		

Examiner Signature	James L. Leybourne	Date Considered	9/14/04

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Sheet 3 of 4

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Application Number	10/679,100
Filing Date	October 3. 2003
First Named Inventor	Steve Berger
Art Unit	2881
Examiner Name	James L. Leybourne
Attorney Docket Number	MIM-087.02

NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No.[1]	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T[2]
JLL	AH	Slingerland, H.N., Barth, J.E., Koets, E. Kramer, J. van der Mast, K.D., " Propasal for a Second Generation IBPG," Proceedings Microcircuit Engineering Conference, 1984, Microcurcuit Engineering,1985, pp. 381-387	
JLL	AI	Slingerland, H.N., Bohlander, J.H., van der Mast, K.D., Koets, E., " Progress on the Delft Ion Beam Pattern Generator," Microelectronic Engineering 5 (1986), Elsevier Science Publishers B.V (North Holland), pp 155-161	
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JLL	AL	van der Mast, K.D., Pijper, F.J., and Barth, J.E., " A Flexible Beamshaper." MicroelectronicEngineering 5 (1986), Elsevier Science Publishers B.V. (North Holland), pp 115-122	
JLL	AM	Vijgen. L., "Coulomb Interactions In Focused Ion Beam Columns," 3 Beams Conference 1992.	
JLL	AN	R.S. Longhurst, Geometrical and Physical Optics, 3rd Edition (Longman, London) pp. 333.	
JLL	AO	P. Hawkes and E. Kasper, Principles of Electron Optics, Vol. 2 (Academic Press, London) Chapter 43	
JLL	AP	L. Vijgen and P. Krull, Coloumb Interactions in a Shaped Ion Beam Pattern Generator. J. Vac. Sci Tech. B 10 (6), 2809 (1992)	
JLL	AQ	K. Edinger, V. Yun, J. Melngailis, and J. Orloff. Development of a High Brightness Gas Field Ion SOurce. J. Vac. Sci. Tech. B 15(6), 2365(1997)	

Examiner Signature	James L. Leybourne	Date Considered	9/14/04

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JLL	X	Bauer, E., Koziol, C., Lilienkamp, G., Schmidt, T., " Spectromicroscopy in a Low Energy Electron Microscope," Journal of Electron Spectroscopy and Related Phenomena 84 (1997) pp 201-209	
JLL	Y	Edinger, Klaus and Krans, Thomas, "Modeling of Focused IOn Beam Induced Surface Chemistry," Journal of Vacuum Science Technology B 18(6), Nov/Dec 2000; pp 3190-3193	
JLL	Z	Hawkes, P.W. and Kasper, E., Principles of Electron Optics, Vol.2.. Applied Geometrical Optics, Academic Press, 1989: Chapters 47, 48 pp 971-1003.	
JLL	AA	Orloff, J., Li. J.Z., Sato, M., "Experimental Study of a Focused Ion Beam Probe Size and Comparision with Theory," Journal of Vacuum Science Technology, B9 (5), Sep/Oct 1991, pp 2609-2612	
JLL	AB	Orloff, J., and Sudraund, Pierre, " Design of a 100 kV, High Resolution Focused Ion Beam Column with a Liquid Metal Ion Source," Microelectronic Engineering 3 (1985) pp. 161-165	
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JLL	AD	"Plasmaion SOurce-ECR microwave plasma ion sournce," http://www.tectra.de/plasma-ion-source.htm, Feb 18, 2000 Contact: Dr. Christian Bradley, tectra GmbH, Reuterweg 85, D-60323 Frankfurt/M.	
JLL	AE	Sato, M., and Orloff, J., " A Method for calculating the Current Density of Charged Particle Beams and the Effect of Finite SOurce Size and Spherical and Chromatic Aberrations on the Focusing Characteristics," Journal of Vacuum Science Technology, B, Vol 9, No. 5, Sep/Oct 1991: pp	
JLL	AF	Stickel, W., " Simulation of Columb Interactions in Electron Beam Lithography Systems-A Comparison of Theoretical Models," Papers from the 42nd International COnference on Electron, Ion, and Photon Beam Technology and Nanofabrication, 26-29 May 1998	
JLL	AG	Singerland, H.N., "Optimization of aChromatically Limited Ion Microprobe," Microelectronic Engineering2 (1984) 219-226	

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JLL	AR	S. Guharay, W. Wang, V. Didnikov, M. Reiser, J. Orloff, and J. Melngailis High-Brightness Ion Source for Ion Projection Lithography, J. Vac. Sci. Tech. B. 14(6), 3907 (1996)	
JLL	AS	Y. Lee, R. Gough. W. Kunkel, K. Leung, L. Perkins, D. Pickard, L. Sun, J. Vujic, and M. Williams. Development of Ion Sources for Ion Projection Lithography, J. Vac. Sci. Tech. B 14(6). 3947 (1996)	

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